

# ECLIPSE MA200 MA100N

Inverted Metallurgical Microscopes



## ECLIPSE MA200/MA100N

Mikon CLIPPA Maleoo

Features

# **MA200**

Offers high stability, durability, and a smaller footprint than conventional models, as well as easy access to the stage handle, the nosepiece, the BF/DF change lever, and diaphragms, all located on the front side.

	Brightfi	eld Darkfield	Simple polarizing	DIC	Fluorescence	
Compatible observation	0	0	0	0	$\triangle$	
methods	*DIA illuminator is available for transmitted light observation. $\triangle$ : only available with Halogen Lamp and Fiber Illumination					
Compatible illminators	<ul> <li>LV-LH50PC 12V50W Halogen Lamp Illuminator</li> <li>C-HGFI HG Precentered Fiber Illuminator (option)</li> <li>LV-LL LED Lamphouse</li> </ul>					
Magnification module	• 1x/1.5x/2x					
Compatible stages	<ul> <li>MA2-SR Mechanical Stage (stroke: 50 x 50 mm)</li> </ul>					



# **MA100N**

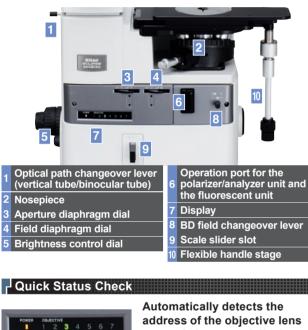
Designated for brightfield and simple polarizing observation, the MA100 is a cost-effective solution to manufacturing and QA/QC situations in industries such as automotive/electronic parts and industrial machinery/tools.

Brightfield	Darkfield	Simple polarizing	DIC	Fluorescence	
$\bigcirc$	-	0	—	—	
*Dedicated reflect	ted illumination m	nodels.			
High-inten	sity white LEI	D Illuminator (	internal powe	er supply)	
MA-SR-N Rectangular 3-plate Stage N (stroke: 50 x 50 mm)					
<ul> <li>MA-SP-N Plain Stage N</li> <li>TS2-S- SM Mechanical Stage (stroke: 126 x 78 mm)</li> </ul>					
<ul> <li>MA-SP-N F</li> <li>TS2-S- SM</li> </ul>	Mechanical S	Stage (stroke: 1 vith MA-SP-N PI			



## Front Operation

Delivers ease-of-use by placing all important controls at the front of MA200N.



address of the objective lens currently in use and displays it on the main unit front panel.

The observation position of the objective lens and sample can be checked easily from the microscope's front panel.

## **Box Structure**

The unique box structure is 1/3 smaller than conventional models and offers improved durability.

#### Compact structure with a depth of 315 mm

A box shaped microscope, not only the width but also the depth is reduced dramatically: The foot print is only onethird of the conventional model!

#### High stability and durability

Reduced vibration during high-power observation, offering a highly rigid microscope.

# Evolved Optical Performance

Provides a more ergonomic observation with clearer images.

#### Super-wide field of view

A sample with a diameter of just 25 mm can be observed in an one field of view by combining the ultra wide field of view evepiece and 1x objective lens.



#### Even Illumination

Improved uniformity of illumination delivers clear images, especially for digital imaging.

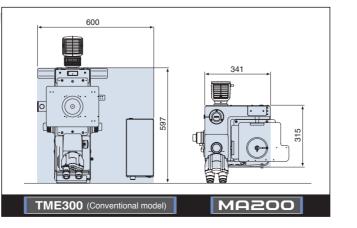
#### Combine images with the stitching feature

Can combine up to eight images with uniform lighting and no seams.



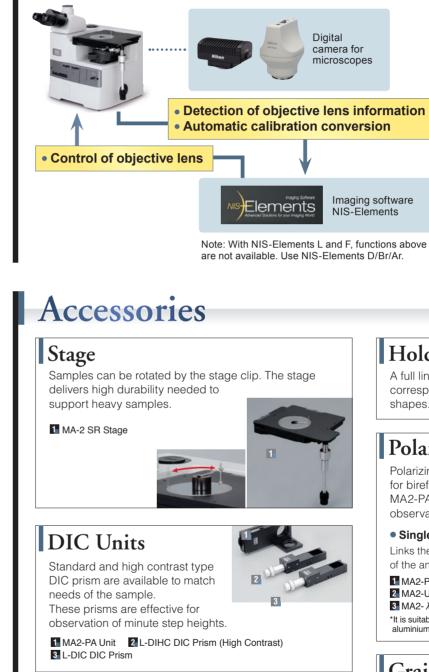
13.3

MA200's field



## **Combination** with **Digital Camera**

The MA200 allows detection of information and control of objective lenses, enabling optimization of the conditions vital for image acquisition.



### Nosepiece & Magnification Module

Enables communication of objective lens position, magnification and intermediate magnification module information with the NIS-Elements image software.

1 MA2-MC Magnification Module 2 LV-NU5I Intelligent Universal Quintuple Nosepiece



Imaging software

## Illumination

### **Expanded** lineup

Added a compact LED illuminator to the existing lineup. With the use of LED. Nikon illuminators are power saving and achieve long life.



LV-LL LED Lamphouse

### Holders

A full lineup is available that correspond to a variety of sample shapes.

## **Polarizing Units**

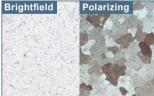
Polarizing observation is effective for birefringence samples. MA2-PA unit is suitable for observation of aluminium.

Single-action operation Links the attachment/release of the analyzer/polarizer.

1 MA2-PA Unit 2 MA2-UPA Unit\* 3 MA2-λP λ Plate \*It is suitable for inspecting aluminium sample.







## Grain Size Reticle & Scale

Overlays a pattern onto the observed image. The Grain Size Reticle is used for grain size analysis and complies with the JIS G0551 and ASTM E112 standards. The Scale displays a scale for each objective lens magnification.

1 MA2-GR Grain Size Reticle JIS G0551/objective lense 10x (100× magnification) ASTM E112/objective lense 10x (100× magnification) 2 MA2-MR Scale



## ECLIPSE MA100N

A durable, user-friendly Inverted Microscope with superior image quality, a small footprint and great cost performance.

## Illumination

Employment of high-intensity LED illumination (Eco-illumination)

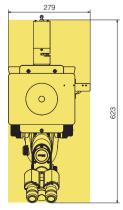
Compared to conventional halogen illumination, these high intensity LED sources need only about one third of consuming electricity and last approximately 30 times longer. The MA100N ensures stable sample observation with uniform color temperature even in different light intensity.

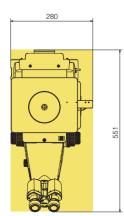


# Compact Body

Redesigned to be smaller

Designed for LED illumination, the footprint is 11% smaller than conventional models, allowing users to have more installation choices.





Previous model (MA100L)

**MA100N** 

## Stage

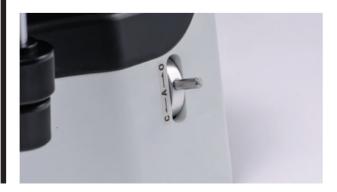
Controlled stability even with heavy samples/ Boasts superior durability

The MA-SR-N Rectangular Stage was developed especially for the MA100N. The three-plate structure allows for observation of heavy samples, such as a grinder resin mounted samples.



## Aperture Diaphragm Standard with MA100N

The epi illuminator comes standard with a variable aperture diaphragm to control image contrast and depth of field.



## Accessories



## **Digital Camera**

Redesigned with optical systems suitable for sample observations. The camera port is located on the side of MA100N to provide improved visibility of the stage.

Microscope Camera DS-Fi3 3 TS2-P-CF Camera port 100 2 C-0.63x-TS2 C-mount Adapter







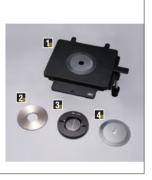
## Basic stage set

A triple-platform stage structure lets you use heavy samples.

MA-SR-N Rectangular Stage N 2 Specimen Holder

(ø20/30/40 mm aperture) 3 MA-SH3 Specimen Holder 3

4 MA-SRSH1 Universal Specimen Holder



### Grain size reticle

The class of grain size in a sample can be easily distinguished while observing its image.

MA100-EPRGS Grain Size Reticle



### Other accessories 7 MA-SRSH1 Universal 1 TI-SM Mechanical Stage CH Specimen Holder 2 MA-SP-N Plain Stage N 8 MA-SH1-N Specimen 3 MA-SH2-N Specimen Holder 2N Holder 1N 4 MA-S-HU Universal Holder 9 MA-P/A Simple 5 MA-SH3 Specimen Holder 3 Polarizer 6 MA-SRSH 25-40 Holder

## Accessories

# **CF60-2**

Nikon's CFI60 optical systems are highly evaluated for their unique concept of high NA combined with a long working distance. These lenses have been developed further and evolved achieving the apex in long working distance specifications, correct chromatic aberration, and an optimized lens weight.

Standard objective lenses TU Plan Fluor Series EPI/BD 5x/10x/20x/50x/100x

### Enable brightfield, darkfield, simple

polarizing, sensitive polarizing, differential interference, and epi-fluorescence observations with just one

lens. Achieves superior chromatic aberration performance with long working distance for all magnifications to adapt to any application.



\*Brightfield observation (EPI) objective lens

Light weight

ly-eye

Model	Magnification	NA	Working Distance (mm)
TU Plan Fluor EPI	5×	0.15	23.5
(brightfield type)	10×	0.30	17.5
	20×	0.45	4.5
	50×	0.80	1.0
	100×	0.90	1.0
TU Plan Fluor BD	5×	0.15	18.0
(brightfield/ darkfield type)	10×	0.30	15.0
	20×	0.45	4.5
	50×	0.80	1.0
	100×	0.90	1.0

#### Long working distance objective lenses

#### **TU Plan ELWD** Series EPI/BD 20x/50x/100x

With the phase Fresnel lenses, these objective lenses enable long working distances while

offering higher level chromatic aberration correction than conventional objective lenses. This improves operability for samples with different heights



Light weigh

\*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance (mm)
TU Plan EPI ELWD	20×	0.4	19.0
(brightfield type)	50×	0.6	11.0
	100×	0.8	4.5
TU Plan BD ELWD	20×	0.4	19.0
(brightfield/ darkfield type)	50×	0.6	11.0
	100×	0.8	4.5

### Low-magnification objective lenses

### T Plan EPI IIX/2.5x

Both clear observation using a conventional analyzer/polarizer and operability-oriented observation without the need of an analyzer/ polarizer are possible.



Model	Magnification	NA	Working Distance (mm)
T Plan EPI	1×	0.03	3.8
(brightfield type)	2.5×	0.075	6.5

Apochromatic objective lenses TU Plan Apo Series

### EPI/BD 50x/100x/150x

By using phase Fresnel lenses, these objective lenses achieve significantly longer operating distances while maintaining the superior chromatic aberration performance of apochromatic lenses



objective lens

Model	Magnification	NA	Working Distance (mm)
TU Plan Apo EPI	50×	0.8	2.0
(brightfield type)	100×	0.9	2.0
	150×	0.9	1.5
TU Plan Apo BD	50×	0.8	2.0
(brightfield/ darkfield type)	100×	0.9	2.0
	150×	0.9	1.5

#### Other Lenses Brightfield objective lense CFI L Plan EPI 40x A 40x objective lens is best for metal analysis.

NA: 0.65 W.D.: 1.0 mm





\*Brightfield observation (EPI)

Nodel	Magnification	NA	Working Distance (mm)
TU Plan Apo EPI	50×	0.8	2.0
brightfield type)	100×	0.9	2.0
	150×	0.9	1.5
ΓU Plan Apo BD	50×	0.8	2.0
brightfield/ darkfield type)	100×	0.9	2.0
	150×	0.9	1.5

### Digital camera system for microscopes **DIGITAL SIGHT SERIES**

Microscope camera

### Digital Sight 1000

Equipped with a 2 megapixel CMOS image sensor, it can capture full HD microscope images. By connecting a microscope to this camera and HDMI monitor, movies and images can be captured and saved onto a preinserted SD card in the camera.



1920×1080	0

### Imaging software **NIS-Elements**

L

Using a tablet PC

Max Recordable

Pixels



Simply installing NIS-Elements L on a tablet PC enables setting and control of Digital Sight 1000/DS-Fi3/DS-Ri2

microscope cameras, live image display, and image acquisition.

#### A wide variety of tools

NIS-Elements L enables the conducting of simple measurements on images, with input of lines and comments. These can also be written onto and saved with the image, and measurement data can be output.

Measurement fun	oction	
<ul><li>Line distance</li><li>Area</li><li>Circle</li></ul>	<ul> <li>Circle disance</li> <li>Pitch distance</li> <li>Angle</li> </ul>	Length= 6168.28 µm
Annotate function	1	and the second sec
<ul><li>∠ Line</li><li>∠ Arrow</li><li>▲ Text</li></ul>	Marker Polyline	

#### Scene Mode

Ten camera setting patterns for optimal color reproduction and contrast for each microscope light source, observation method and type of sample, as well as custom settings, can be selected.

• Wafer/IC	<ul> <li>Metal, Ceramic/Plastic</li> </ul>
<ul> <li>Circuit board</li> </ul>	<ul> <li>Flat Panel Display</li> </ul>

\* See the "Digital Camera Digital Sight Series for Microscopes" brochure for details on Digital Sight features.



## DS-Fi3

Three main features of the previous models, highresolution, high sensitivity and low noise, and high-speed live display are offered in 1 camera.

## DS-Ri2

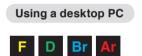
Capable of expressing images as is, this microscope digital camera offers high resolution, color reproduction,

and frame rate

2880×2048

4908×3264



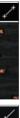


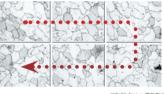


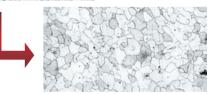
#### Image Stitching

Stitches together images acquired from multiple fields of view to create one image







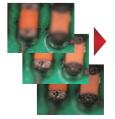




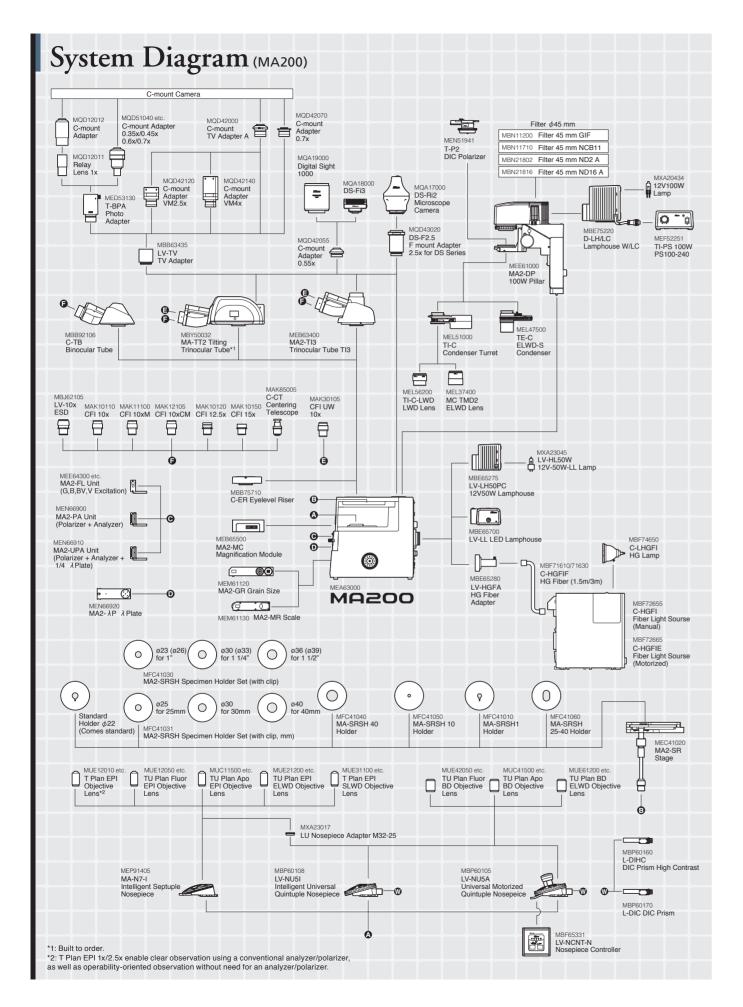
EDF (Extended Depth of Focus)

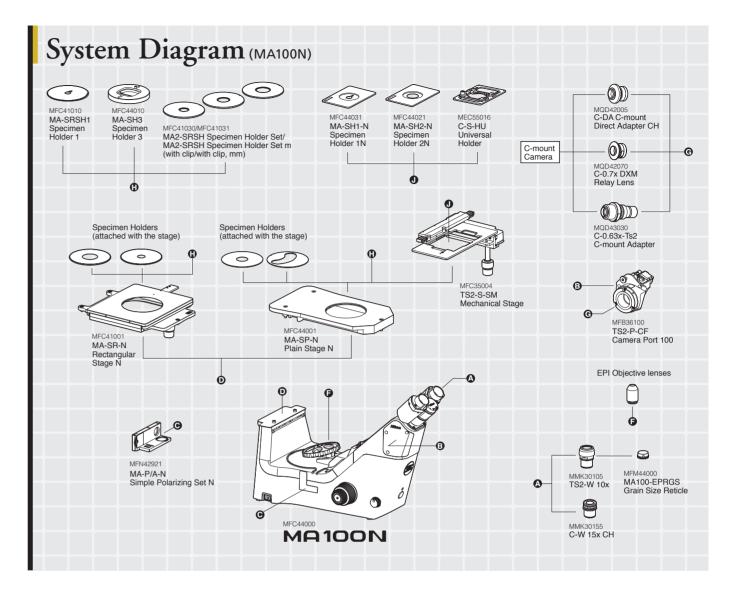
Create a single, all-in-focus image from images of differing focus



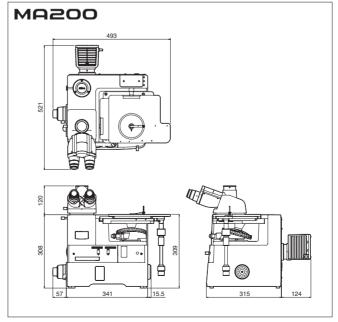


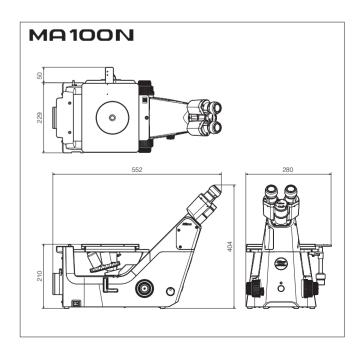






Dimensions





#### Specifications (MA200)

		MA200	
Main body	Focusing mechanism	Focusing nosepiece (Fixed stage) Coaxial coarse/fine adjustment knob (torque adjustable)	
		Coarse adjustment of 4.0 mm per rotation, fine adjustment of 0.1 mm per rotation	
	Illumination	With flare prevention, Built in UV cut filter	
		Field diaphragm: dialing continuous variable (centerable), Aperture diaphragm: dialing continuous variable (centerable)	
		Filter: Double turret (ND16, ND4/GIF, NCB, Additional option available), Polarizing block (Selectable with or without 1/4 $\lambda$ Plate)	
		Fluorescence filter blocks: B/G/V/BV	
		12V50W Halogen Lamp, C-HGFI HG Fiber Illuminator, LV-LL LED Lamphouse	
	Light distribution	Eyepiece tube/Back port: 100/0, 55/45	
Optics	CFIeo/CFIeo-2 system		
Observation image	Surface Image		
Observation method	Bright/Darkfield/Simple Polarizing/DIC/Epi-Fluorescence		
Revolving nosepieces	LV-NU51: Bright/Darkfield/DIC 5 position nosepiece, LV-NU5A: Motorized Bright/Darkfield/DIC 5 position nosepiece		
	MA-N7-I Brightfield 7 position nosepiece (Intelligent)		
Stage	MA2-SR Mechanical Sta	age (X/Y flexible handle)	
	Dimension: 295×215 mm	n, Stroke: 50 mm×50 mm (with distance graduation), Standard accessory: ø22 universal specimen holder (with sample clip)_	
Trinocular eyepiece	Siedentopf interpupillary	/ distance adjustment 50-75 mm	
Power source	100-240 V, 50-60 Hz		
Power consumption (max.)	1.2 A 75 W		
Weight	Approx. 26 kg (depends	on combination)	
Options	Intermediate magnification	Turret (1x, 1.5x, 2x), Status detection (Output magnification information to main unit)	
	Scale	MA2-GR Grain Reticle (ASTM E112-63 grain sizing numbers 1 to 8), Grid Reticle(20 lines, 0.5 mm)	
		MA2-MR Scale Reticle (compatible with 5-100×, Read in um, Dialing System)	

#### Specifications (MA100N)

	MA 100N				
Optics	CFIeo/CFIeo-2 system				
Observation image	Reversed image				
<b>Observation method</b>	Brightfield and polarization (with MA P/A simple polarizer/analyzer set)				
Focusing	Focusing nosepiece (fixed stage), coaxial coarse/fine adjustment knob with 8.5-mm stroke				
	(Coarse adjustment of 37.7 mm per rotation, fine adjustment of 0.2 mm per rotation)				
Nosepiece	Brightfield 5-position nosepiece				
Stage	MA-SR-N Rectangular 3-plate Stage N: 50×50 mm stroke (includes two stage inserts (ø20 mm and 40 mm opening) and coaxial control handle on the right side_				
	The 3-plate design allows entire top surface to move. Optional Stage inserts: MA-SRSH1 Specimen Holder 1 with (ø15 mm opening or MA-SH3				
	Specimen Holder 3 with 2 mm to 32 mm adjustable opening				
	MA-SP-N Plain Stage N: 188×310 mm - Includes two stage inserts (1) clear acrylic stage insert with ø30 mm opening, (2) clear acrylic stage insert				
	with crescent opening (width 30 mm) to allow clearance for rotation of high magnification objectives				
	Optional stage inserts: MA-SRSH1 Specimen Holder 1 with 15 mm opening or MA-SH3 Specimen Holder 3 with 2 mm to 32 mm adjustable opening				
	Accepts Attachable Mechanical Stage TI-SM				
	TS2-S-SM Mechanical Stage: 126 mm×78 mm stroke, handle can be attached on the right or left side of the plain stage				
	Optional Specimen Holders to fit Attachable Mechanical stage: MA-SH1-N Specimen Holder 1N (ø15 mm opening)				
	MA-SH2-N Specimen Holder 2N (ø30 mm opening), or C-S-HU Universal Holder (30 mm to 65 mm adjustable opening)				
Illuminator	Internal power supply white LED light source, condenser built-in (lever operated), ø25 mm filter can be inserted				
Binocular body	Built-in Siedentopf binocular, 45 inclination angle and 50 to 75-mm interpupillary adjustment, attachable camera port, eyepiece/Port: 100/0:0/100				
Power consumption (max.)	15W				
Weight	Approx. 10 kg				

#### Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer. July 2020 ©2006-2020 NIKON CORPORATION

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TO ENSURE CORRECT USAGE, READ THE CORRESPONDING MANUALS CAREFULLY BEFORE USING THE EQUIPMENT.



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